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Metryx Wins New Orders For Its Mass Metrology Production Tools

BRISTOL, UK—September 14, 2006—Metryx, Limited, a supplier of mass metrology equipment to the semiconductor manufacturing industry, announced today that it had received orders from three customers for its innovative mass metrology Mentor™ technology. The tools will be deployed in volume production environments to provide process control for a variety of applications.

The orders were received from three different semiconductor manufacturers, one each from Asia, Europe and North America. All three placed orders for the Mentor SF3 and all represented new business for the company.

“More production orders from new customers is simply further validation for our technology,” stated Dr Adrian Kiermasz, President and CEO of Metryx. “Our non-intrusive in-line measuring tools deliver exceptional early warning process control and the accompanying peace of mind that the process is working as it should. There is a great deal of interest in this technology, which is increasingly bringing additional business from both new and existing customers.”

Designed for monitoring critical semiconductor device manufacturing process steps on product wafers in a variety of applications, including memory, logic and power components, Metryx’s Mentor SF3 is a 300mm mass metrology tool offering atomic level repeatability on product wafers with a low cost of ownership and high return on investment.

“We went back to the drawing board to develop our technology and have designed a simple, cost-effective way of measuring whether or not a process is depositing or taking away the material it is supposed to during each respective process step. Semiconductor manufacturers worldwide are now reaping the rewards of this elegant technology as valuable time and money is saved by simply understanding the mass fingerprint of a wafer after every process step,” added Dr. Kiermasz.

Capable of measuring errors in the microgram range, the Mentor SF3 tool monitors the mass of any wafer following a process step to quickly determine whether device manufacture process steps are operating consistently using Passive Data Collection (PDC) and normal distribution analysis. The tool allows process changes to be reliably and accurately determined after deposition, wet or dry etch, or CMP processing.

The small-footprint Mentor SF3 tool is capable of throughputs of 60 wafers per hour to enable nanotechnology mass measurement of production wafers, as well as test and blanket wafers, independent of substrate size or material.

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About Metryx

Metryx is a semiconductor equipment manufacturer specializing in unique nanotechnology mass measurement techniques. Based in Bristol, England, Metryx's non-destructive 200mm and 300mm metrology tools offer atomic layer accuracy making them ideal for material characterization and device manufacture process control. For more information on the company and its products please visit www.metryx.net